

Notice of References Cited		Application/Control No. 10/008,623	Applicant(s)/Patent Under Reexamination SCHULER ET AL.	
		Examiner Alexander Markoff	Art Unit 1746	Page 1 of 1

U.S. PATENT DOCUMENTS

*	Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
A	US-6,085,764	07-2000	Kobayashi et al.	134/147
B	US-5,849,091	12-1998	Skrovan et al.	134/1
C	US-6,048,405	04-2000	Skrovan et al.	134/1
D	US-			
E	US-			
F	US-			
G	US-			
H	US-			
I	US-			
J	US-			
K	US-			
L	US-			
M	US-			

FOREIGN PATENT DOCUMENTS

*	Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
N					
O					
P					
Q					
R					
S					
T					

NON-PATENT DOCUMENTS

*	Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)	
U	Handbook of Semiconductor Wafer Cleaning Technology, Noyes Publications, pages 141 and 142, 1993.	
V		
W		
X		

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.